

VLSI Devices

Lecture 20


Sung-Min Hong (smhong@gist.ac.kr)

Semiconductor Device Simulation Laboratory

Department of Electrical Engineering and Computer Science

Gwangju Institute of Science and Technology (GIST)

Coverage

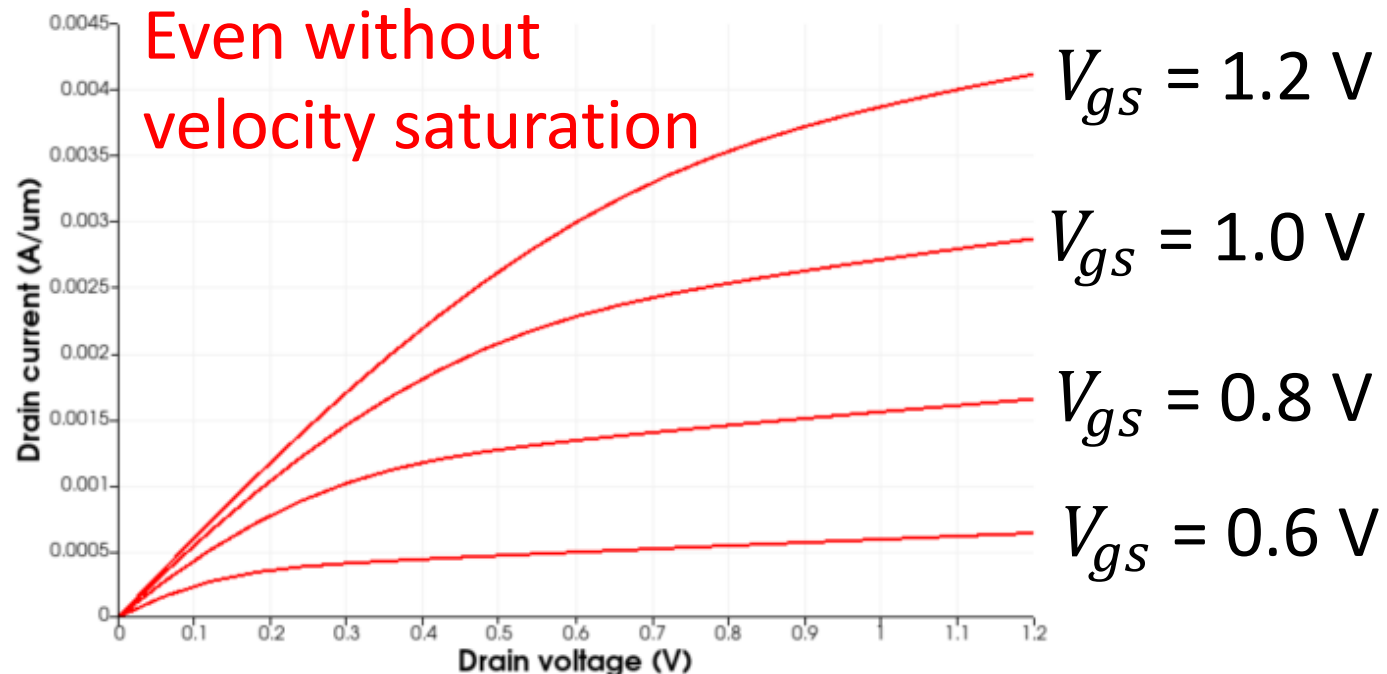
- Two YouTube lectures reserved for advanced topics
 - L14: ~~Substrate bias, channel mobility~~
 - L15: ~~3.2.1~~
 - L16: ~~3.2.1 (Continued)~~
 - L17: ~~Velocity saturation (3.2.2)~~
 - L18: Channel length modulation and so on (3.2.3, 3.2.4, 3.2.5)
 - L19: MOSFET scaling
 -  – L20: MOSFET scaling (Continued)
 - L21: Quantum effect (4.2.4)
 - L22: Double-gate MOSFETs (10.3)
 - L23: FinFETs
 - L24: CFETs

Channel length modulation

- Gradual-channel approximation fails at the saturation point.
 - Distance between the saturation point and the drain, ΔL .
 - Drain current increases as

$$I_d = \frac{I_{dsat}}{1 - (\Delta L/L)}$$

Taur, Eq. (3.101)



Short-channel devices: TSMC 3 nm node

- IEDM 2022 (27.1)

– DIBL versus L

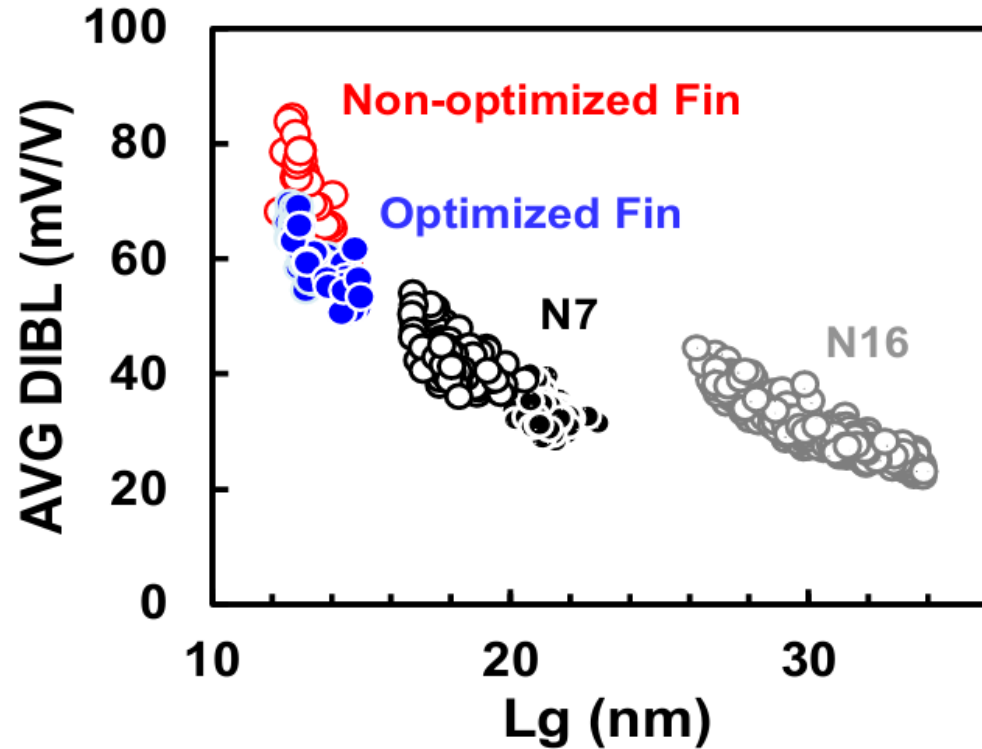


Fig.1 FinFET L_g scaling trend vs DIBL. Fin profile optimization is critical but is at the limit for further L_g scaling.

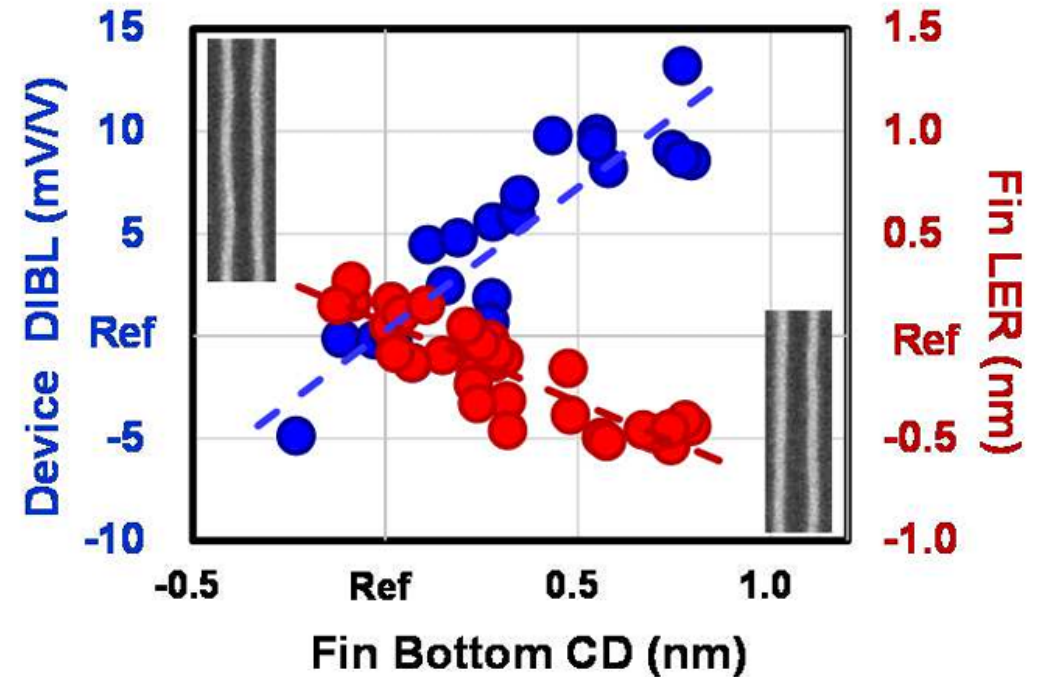


Fig.2 Smaller fin bottom CD reduces DIBL but degrades LER, which is an indicator of fin structural robustness and potential yield impact.

Source-drain series resistance

- Finite silicon resistivity + metal contact resistance
 - MOSFET channel resistance in the linear region

$$R_{ch} = \frac{V_{ds}}{I_d} = \frac{L}{\mu_{eff} C_{inv} W (V_{gs} - V_{on})}$$

Taur, Eq. (3.102)

Scaled contacted gate pitch

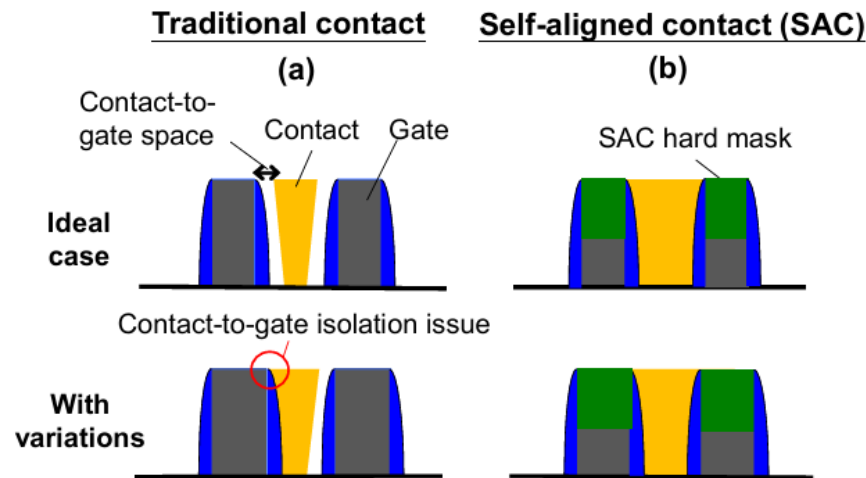
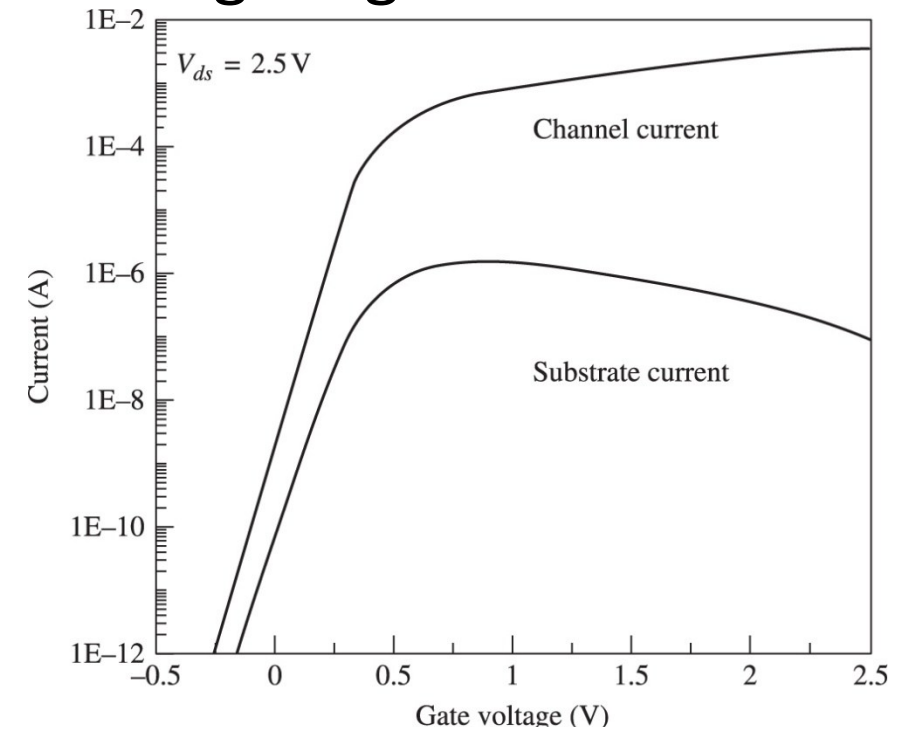
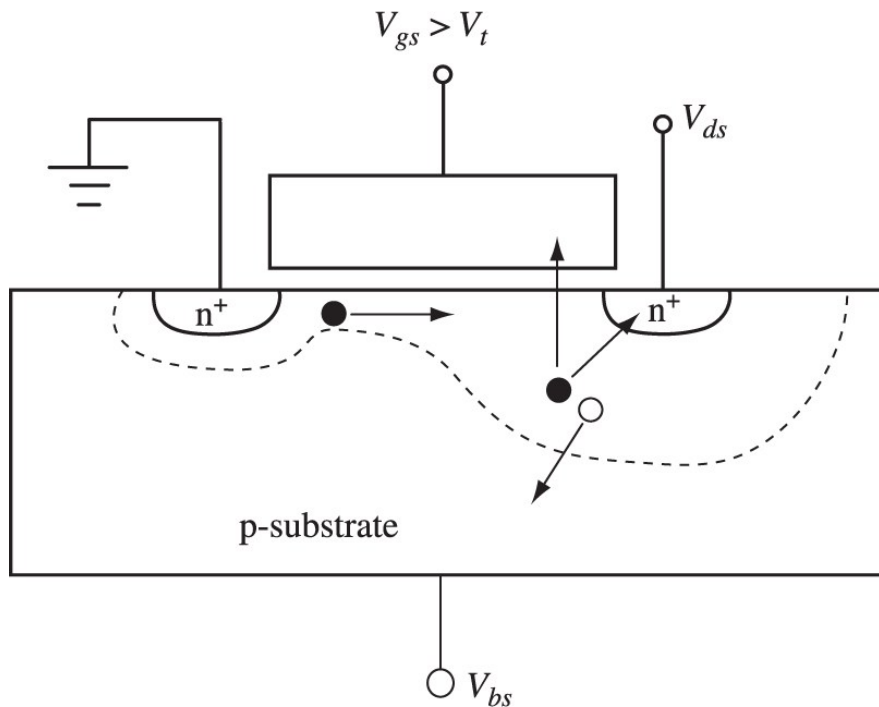


Fig.3 Contact schematics. Traditional contact (a) is vulnerable to variations induced contact-to-gate isolation issues compared to SAC (b).

Self-aligned contact (TSMC, IEDM 2022)

Hot carrier effects

- Electrons gain energy from the electric field.
 - Injection into the SiO₂ layer. Secondary electron/hole pair.
 - $V_{ds} - V_{dsat}$ is the voltage drop in the space-charge region.

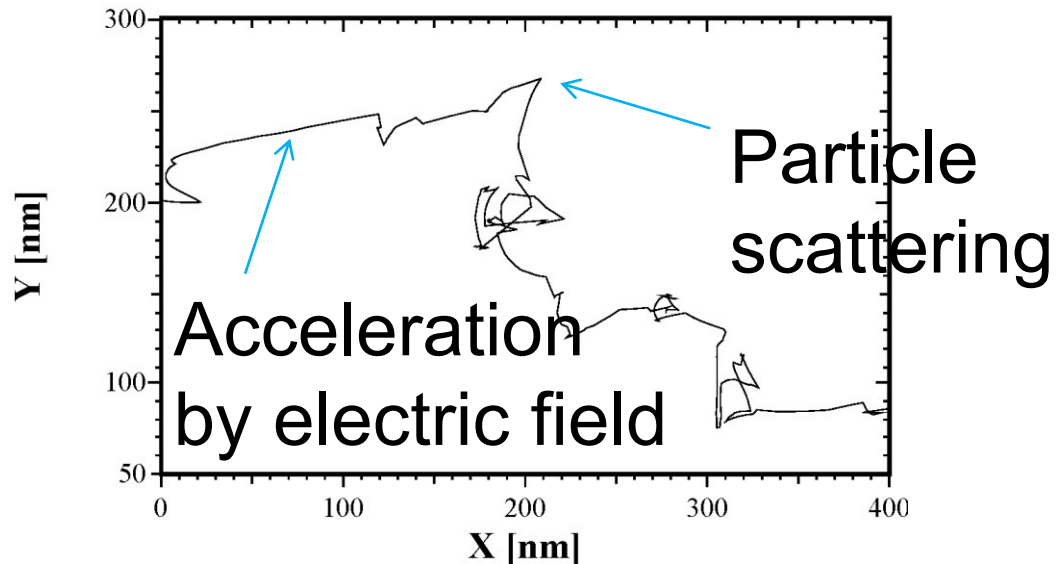


Channel hot-electron (Taur, Fig. 3.33) GIST Lecture

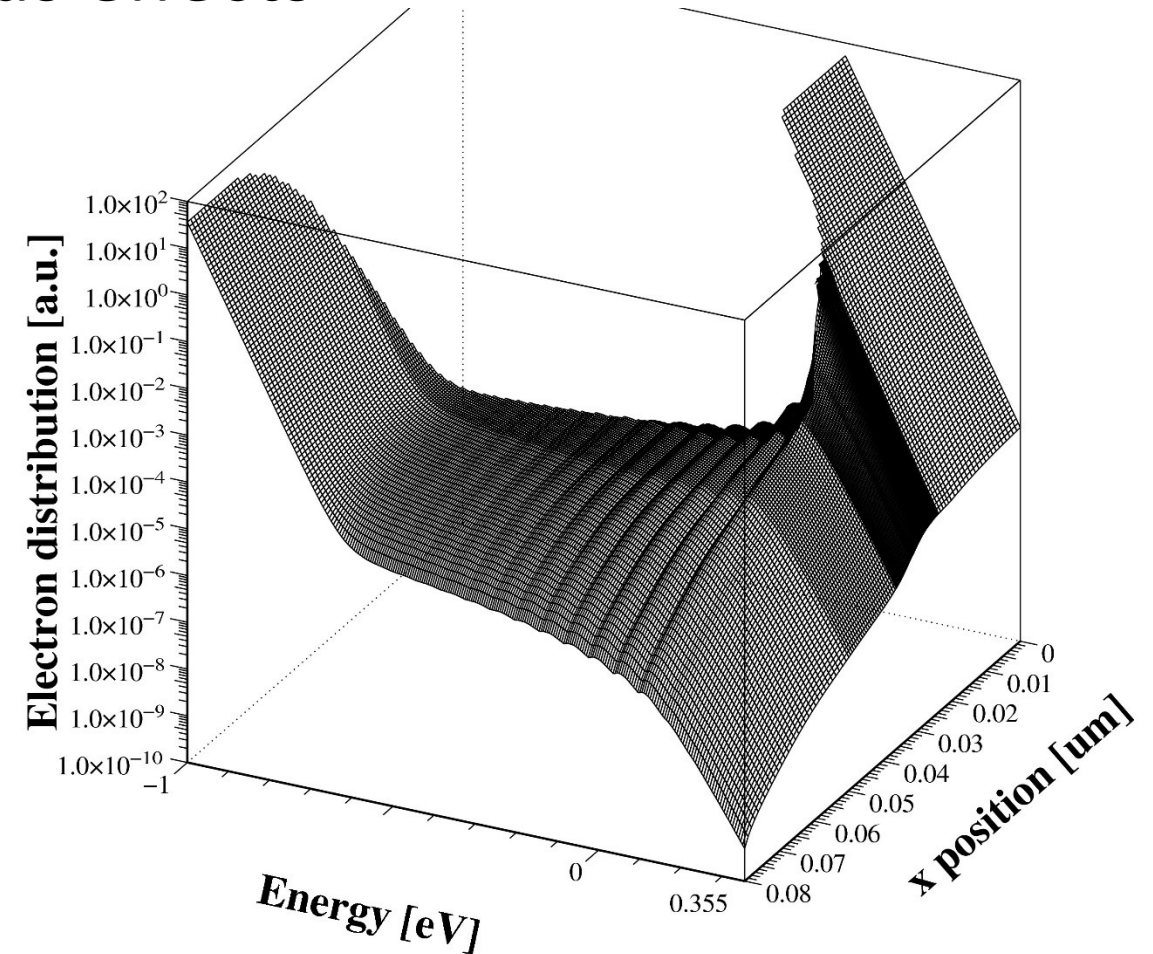
Substrate current (Taur, Fig. 3.34)

Energy distribution, $f(\mathbf{r}, E)$

- Key quantity to understand various effects
 - Various ways to model it
 - Boltzmann transport equation



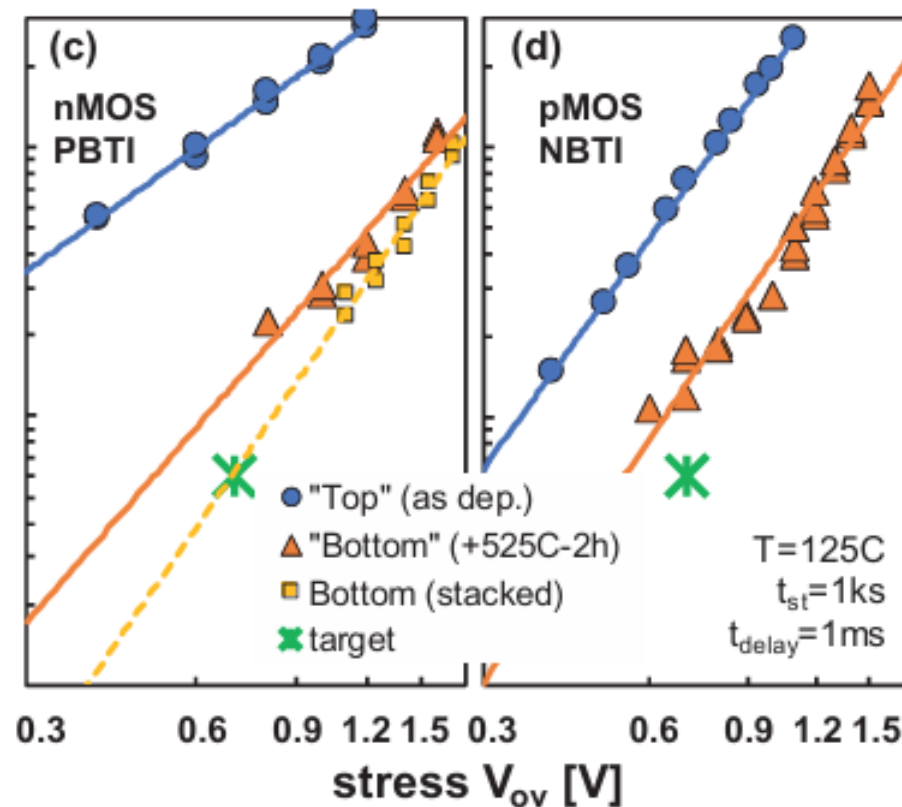
Stochastic electron motion
simulated by Monte Carlo



Distribution function 7

BTI (Bias-Temperature Instability)

- Reliability issue (NBTI in PMOSFETs, PBTI in NMOSFETs)
 - Interface trap generation & $|V_t|$ shift



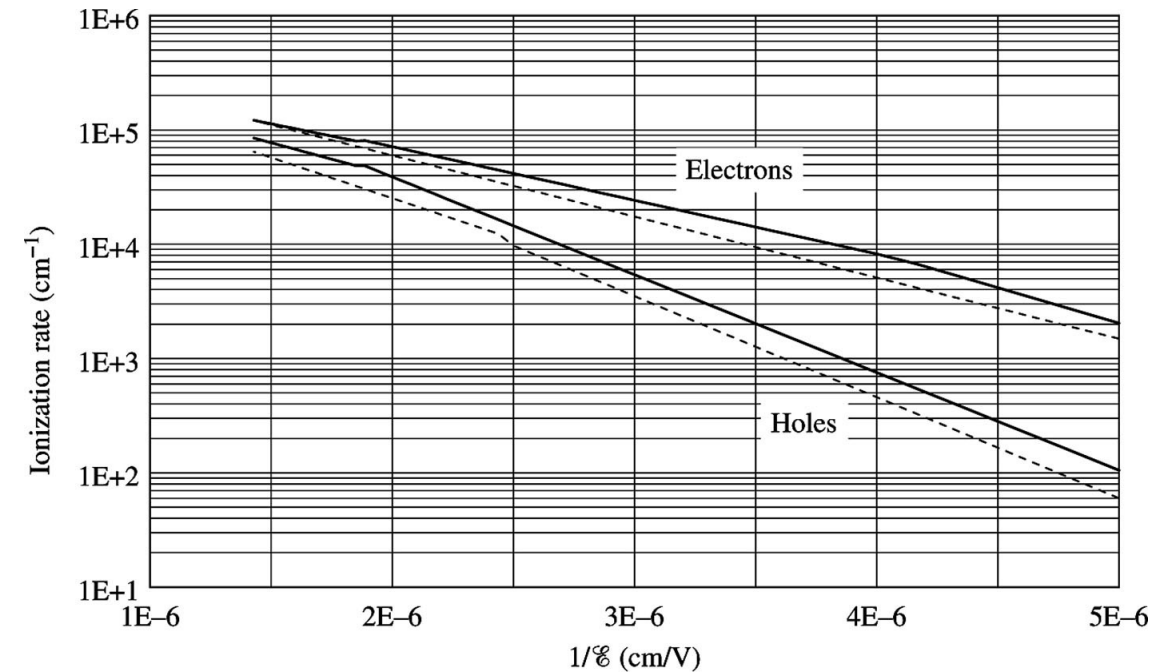
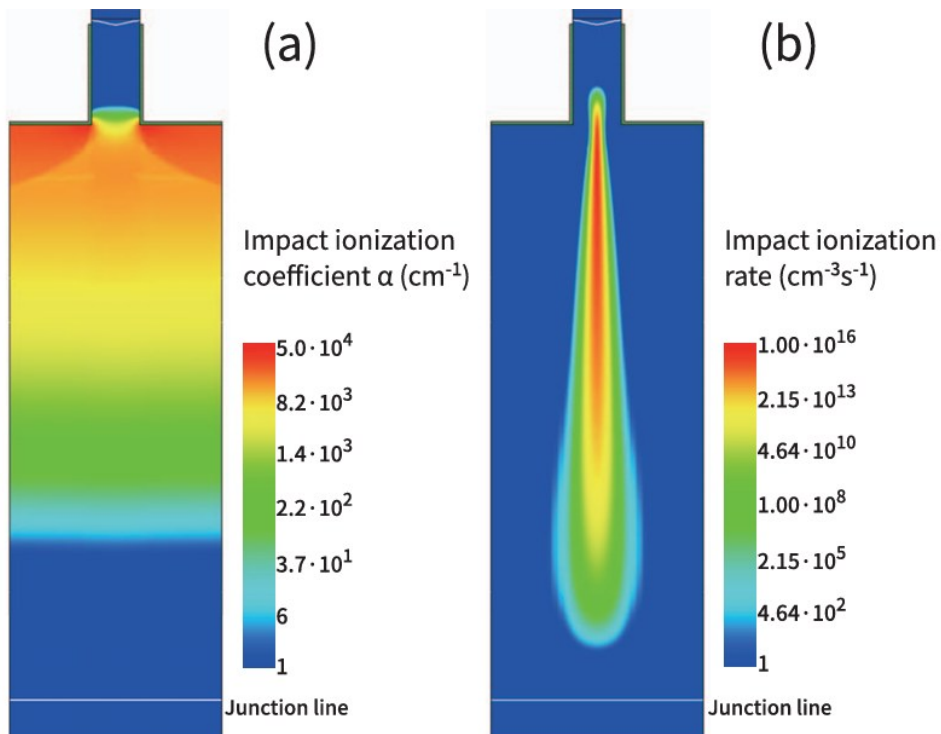
BTI characteristics of gate stacks (IMEC, IEDM 2018)

MOSFET breakdown

- Impact ionization

- Strong dependence on \mathcal{E}

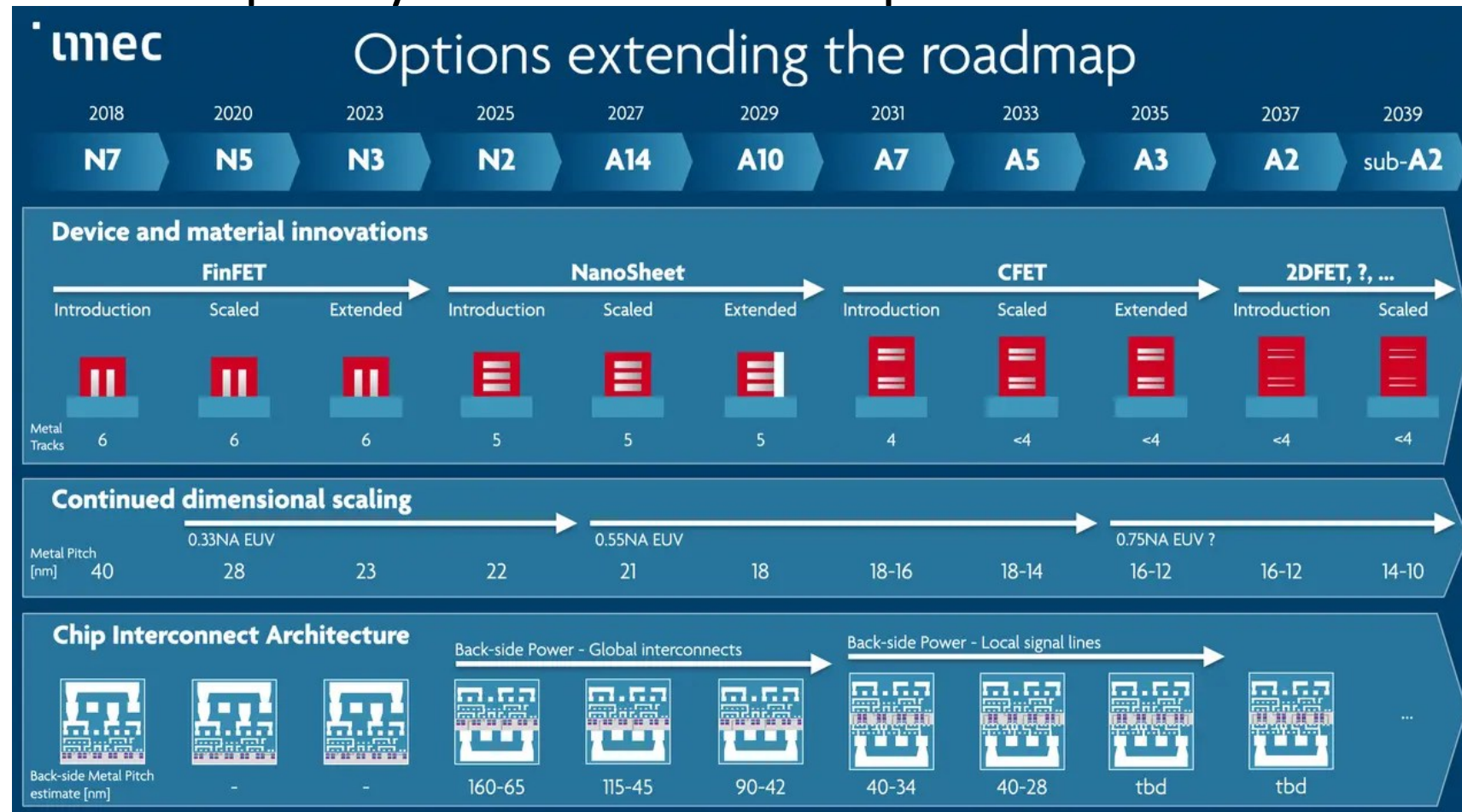
$$\alpha = A \exp\left(-\frac{b}{\mathcal{E}}\right) \text{ Taur, Eq. (2.258)}$$



Impact ionization rates
in silicon (Taur, Fig. 2.59)

MOSFET scaling

- First of all, we must understand the history. (~ 2011)
 - Comtemporary MOSFETs are not planar.



IMEC
roadmap

Thank you!